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Kamimura et al.

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(54) **PRESSING MEMBER FOR SUBSTRATE
POLISHING APPARATUS**

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(30) **Foreign Application Priority Data**

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(52) **U.S. Cl.**
USPC **D15/126**

(58) **Field of Classification Search**
USPC D8/70, 71; D15/126, 138
CPC B24B 9/065; B24B 21/004; B24B 37/27
See application file for complete search history.

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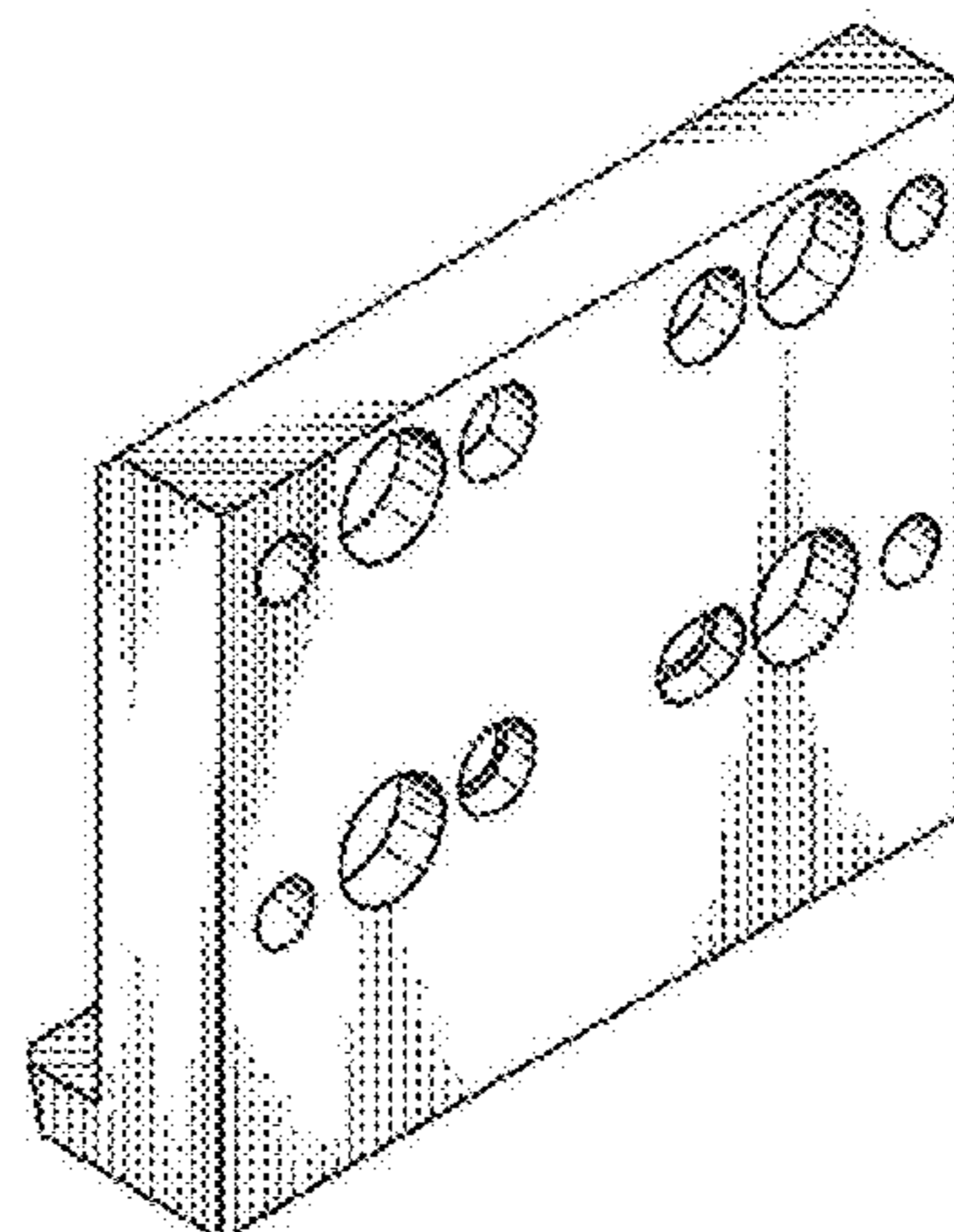
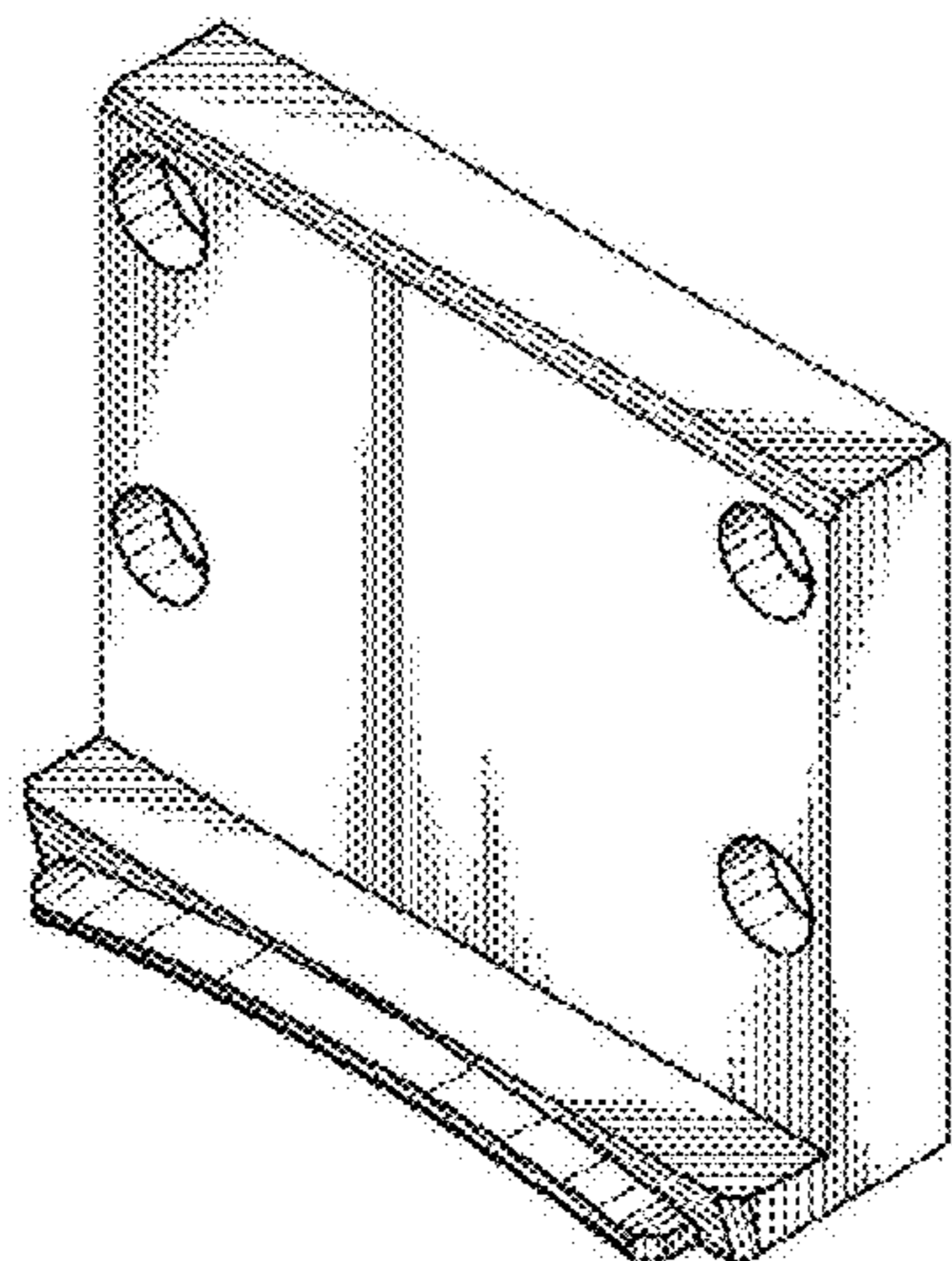
(57) **CLAIM**

The ornamental design for a pressing member for a substrate polishing apparatus, as shown and described.

DESCRIPTION

FIG. 1 is a first perspective view, observed from a front of a pressing member for a substrate polishing apparatus showing our new design;
FIG. 2 is a second perspective view, observed from a rear thereof;
FIG. 3 is a front view thereof;
FIG. 4 is a rear view thereof;
FIG. 5 is a top view thereof;
FIG. 6 is a bottom view thereof; and,
FIG. 7 is a right-side view thereof, a left-side view being a mirror image thereof.

1 Claim, 2 Drawing Sheets



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FIG.1

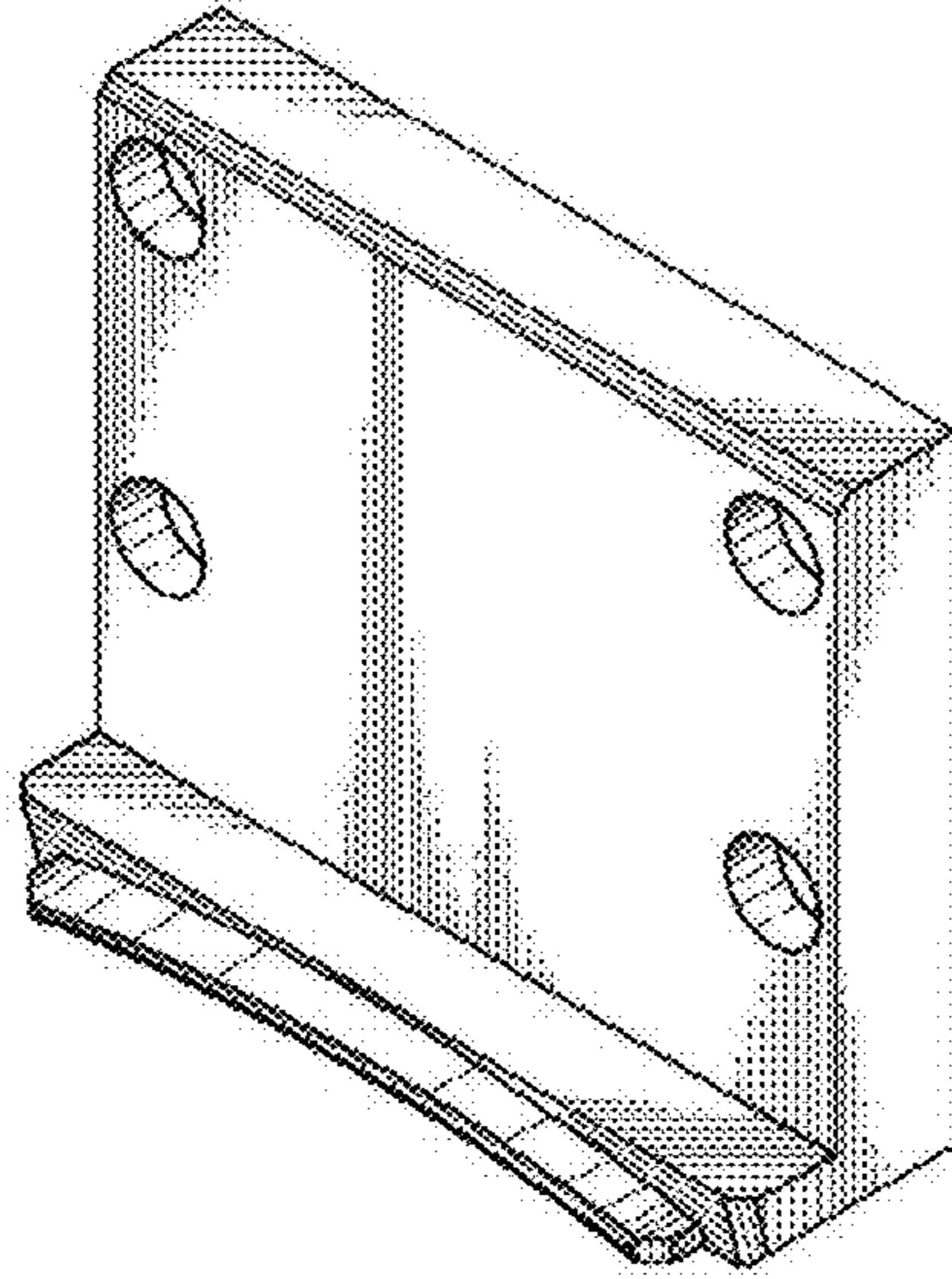


FIG.2

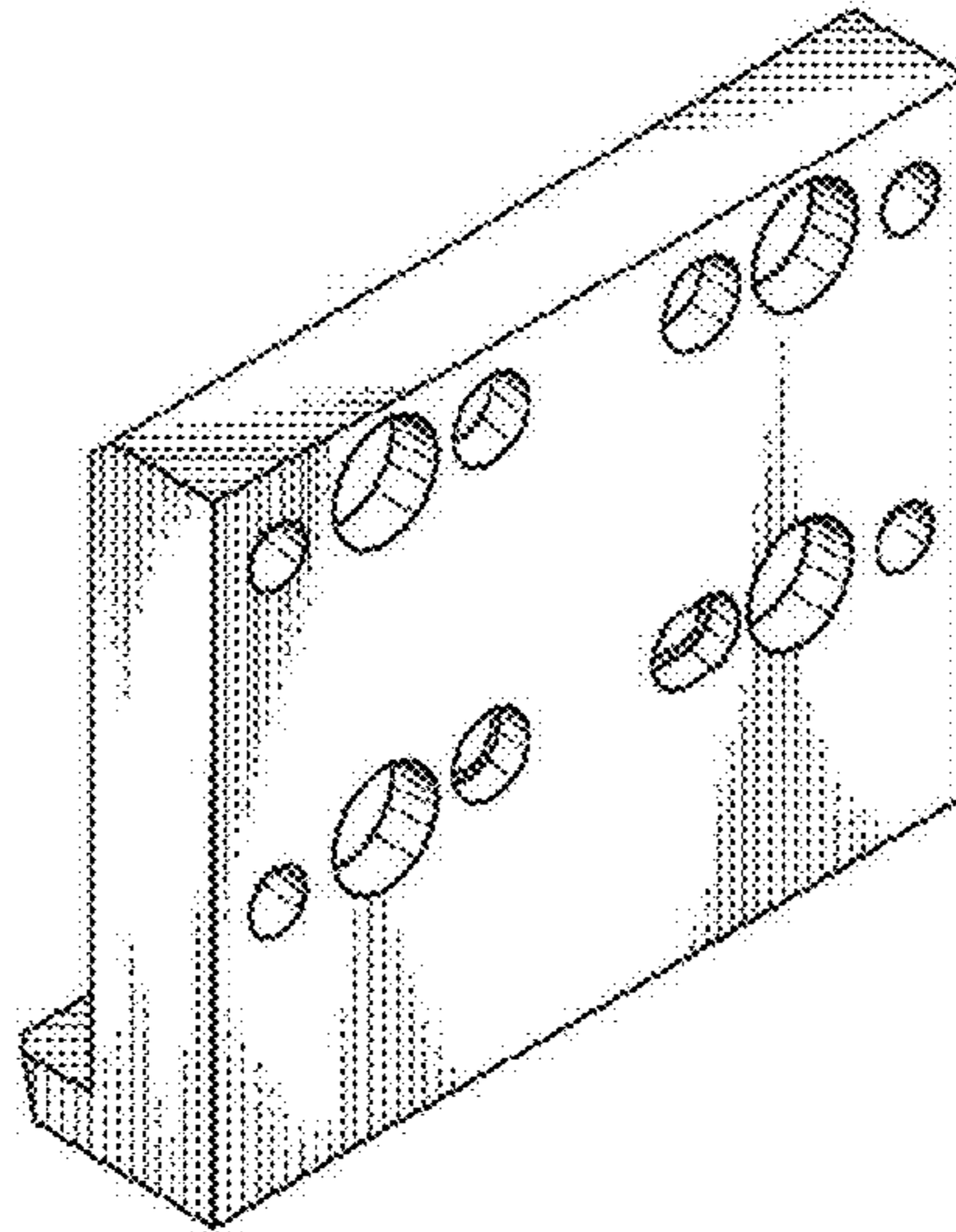


FIG.3

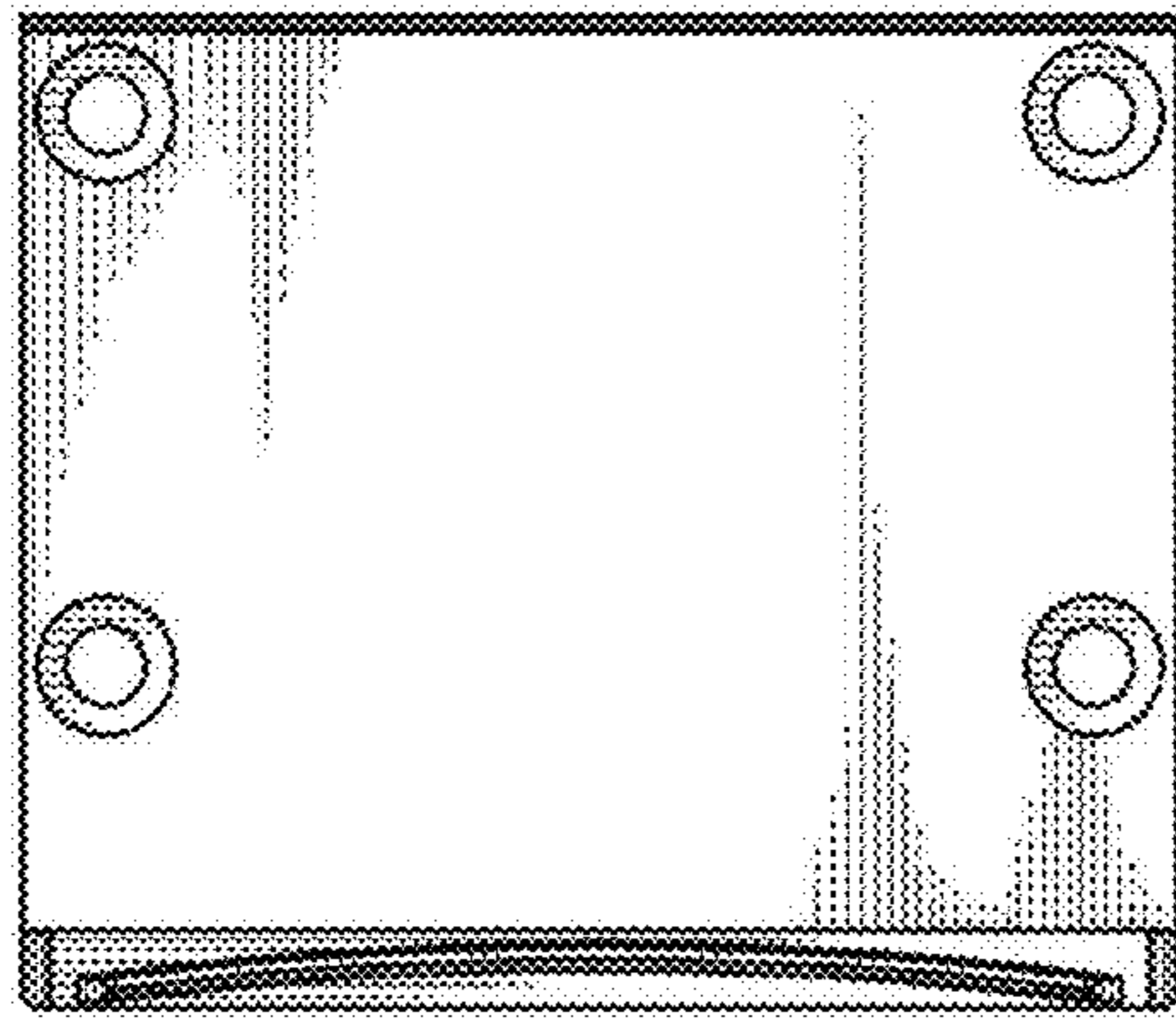


FIG.7

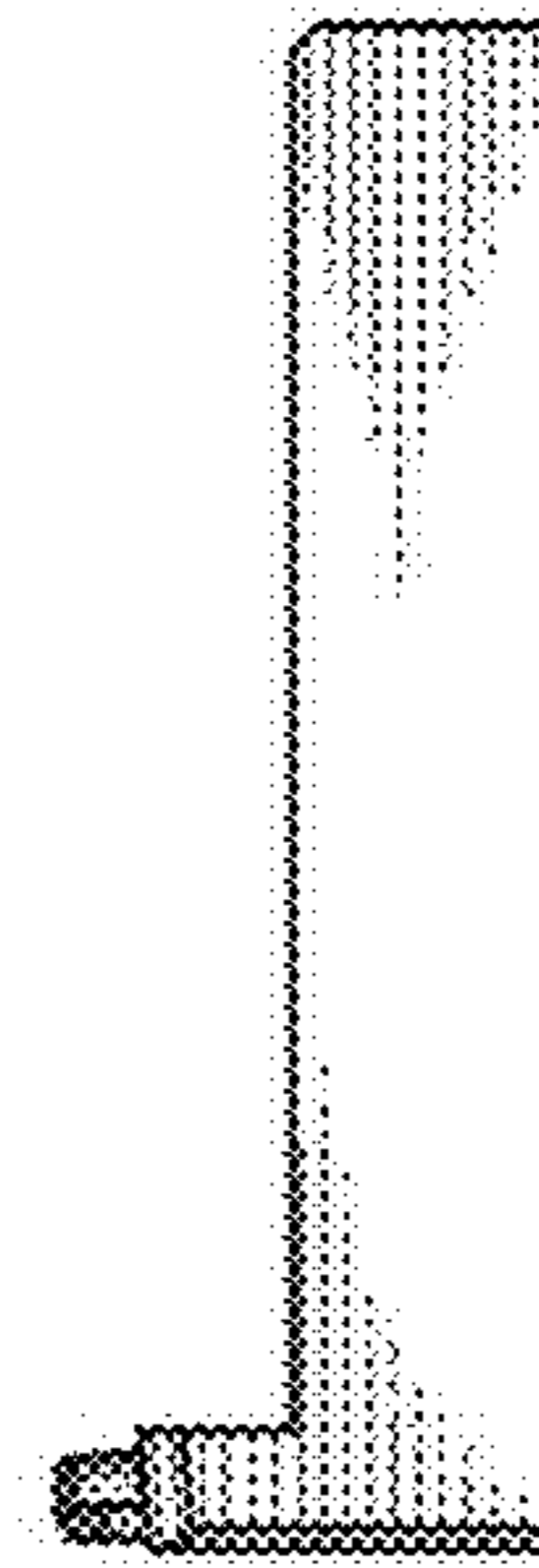


FIG.4

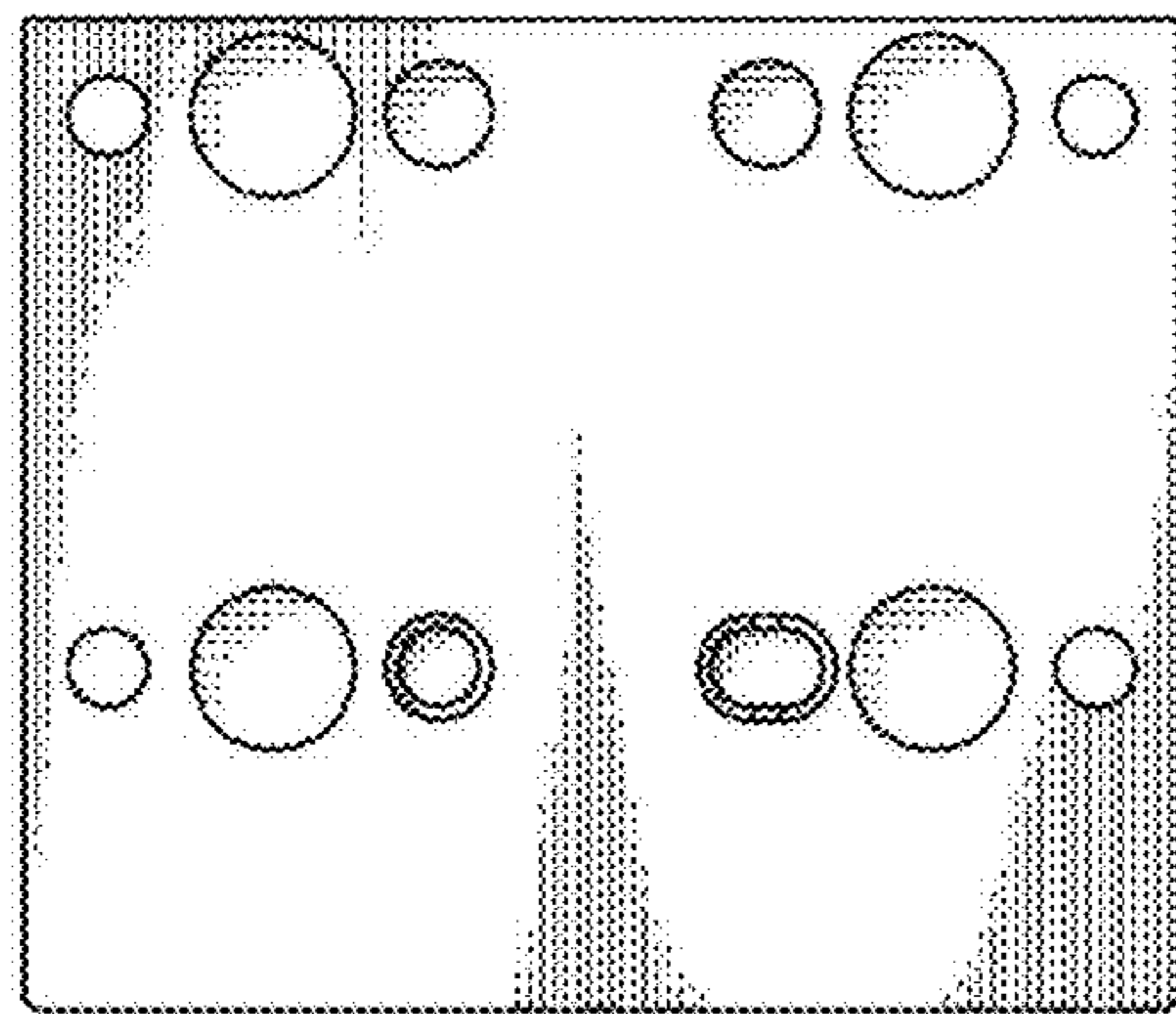


FIG.5

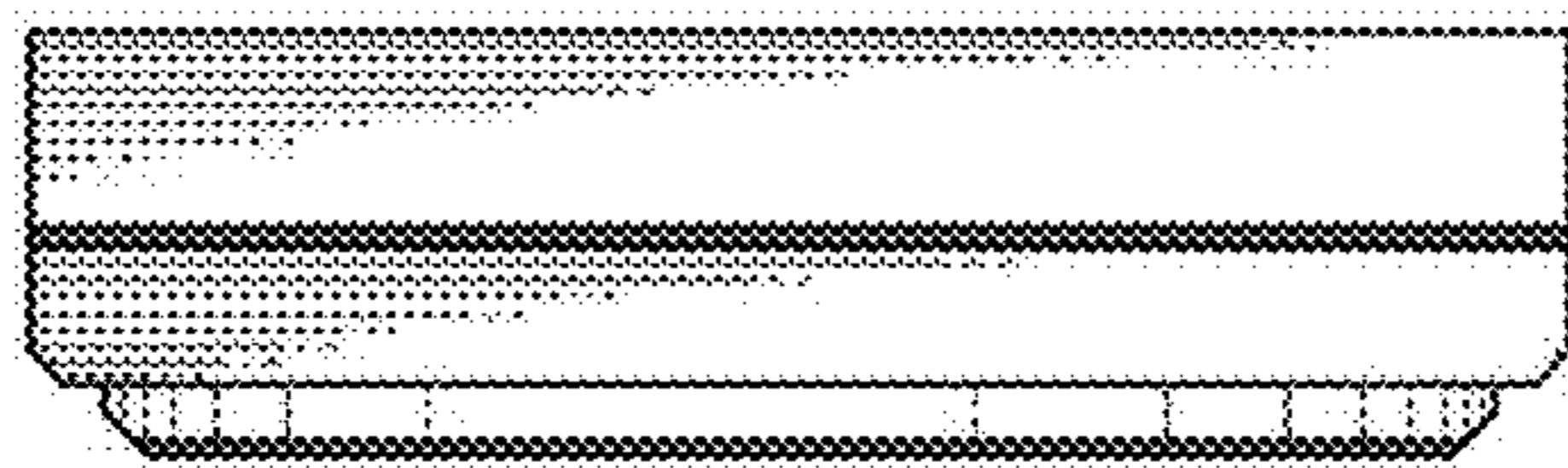


FIG.6

